

<b>Notice of References Cited</b>	Application/Control No. 10/578,805		Applicant(s)/Patent Under Reexamination HAMELINCK ET AL.	
	Examiner YU CHEN		Art Unit 2815	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	C	US-5,867,302	02-1999	Fleming, James G.	359/291
*	D	US-6,384,952 B1	05-2002	Clark et al.	359/224.1
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	M	US-			

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	W	Teter et al., "Precision cryogenic magnetostrictive actuator using a persistent high TC magnet", Journal of Applied Physics, Vol. 87, No. 9, May 2000, pp 6313-6315.
	X	Bifano et al., "Surface Micromachined Deformable Mirrors", Conference on Emerging Technologies and Factory Automation (1996), Vol. 2, pp 393-399.

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.